Technology Center 1795

Amendment dated September 30, 2008

Reply to Office Action dated May 30, 2008

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the

application.

Listing of Claims:

Claim 1 (Currently amended): A system for storing and retrieving

elemental hydrogen, said system comprising:

a housing:

at least one passage connected to said housing for conducting

hydrogen gas into and conducting hydrogen gas out of said housing;

a hydrogen storage member enclosed within said housing, said

hydrogen storage member comprising a mass of porous silicon having interior

and exterior surfaces, at least said interior surfaces having dangling bond sites

at which reversible chemisorption of hydrogen atoms occurs:

releasing means for causing said chemisorbed hydrogen atoms to be

liberated from said dangling bond sites to be released as hydrogen gas from

said housing through said at least one passage; and

a control unit comprising means for receiving inputs indicative of

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operating parameters of said system, and means for issuing outputs that

control said releasing means. system for liberating said chemisorbed

hydrogen atoms from said dangling bond sites and releasing said liberated

hydrogen atoms as hydrogen gas from said housing through said at least one

passage.

Claim 2 (Previously presented): A system in accordance with claim

1 wherein at least said interior surfaces of said porous silicon have dendritic

spikes or etched pits.

Claim 3 (Previously presented): A system in accordance with claim

1 wherein said at least interior surfaces are bare silicon surfaces at which said

dangling bond sites are exposed.

Claim 4 (Original): A system in accordance with claim 1 comprising

a plurality of said hydrogen storage members.

Claim 5 (Currently amended): A system in accordance with claim 1

wherein said porous silicon defines a -surface- layer within -over- at least a first

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surface portion of said hydrogen storage member.

Claim 6 (Original): A system in accordance with claim 5 wherein the

percent void volume of said surface layer is about 50%.

Claim 7 (Previously presented): A system in accordance with claim

5 further comprising electronic integrated circuits on a second surface portion

of said hydrogen storage member.

Claim 8 (Currently amended): A system for storing and retrieving

elemental hydrogen, said system comprising:

a housing;

at least one passage connected to said housing for conducting

hydrogen gas into and conducting hydrogen gas out of said housing;

a hydrogen storage member comprising a porous mesh of crystalline

silicon columns having silicon surfaces with dangling bond sites at which

reversible chemisorption of hydrogen atoms occurs; and

means for liberating said chemisorbed hydrogen atoms from said

dangling bond sites and releasing said liberated hydrogen atoms as hydrogen

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gas from said housing through said at least one passage.

Claim 9 (Currently amended): A system in accordance with claim 8

wherein said silicon columns have surfaces on the (111) plane. have an

aspect ratio of length to diameter of at least 10.

Claim 10 (Previously presented): A system in accordance with

claim 8 wherein said silicon columns are formed by extrusion of molten silicon

to have surfaces on the (111) plane.

Claim 11 (Previously presented): A system in accordance with

claim 10 wherein said silicon columns are extruded through at least one

aperture that is an integral multiple of the lattice spacing of silicon such that

said silicon columns have a minimum energy configuration suitable for forming

a crystal.

Claim 12 (Previously presented): A system in accordance with

claim 8 wherein said silicon columns have diameters of about 1 nm.

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Claim 13 (Previously presented): A system in accordance with

claim 12 wherein said silicon columns have cross-sectional shapes selected

from the group consisting of triangle, rhombus, square, and circle.

Claim 14 (Previously presented): A system in accordance with

claim 10 wherein said silicon columns have roughened surfaces.

Claim 15 (Currently amended): A system in accordance with claim

8 further comprising a control unit comprising means for receiving inputs

indicative of operating parameters of said system, and means for issuing

outputs that control said liberating means. 1 further comprising releasing

means controlled by said control system for causing said chemisorbed

hydrogen atoms to be liberated from said dangling bond sites.

Claim 16 (Previously presented): A system in accordance with

claim 15 wherein said releasing means is selected from the group consisting

of light sources, current sources, voltage sources, and combinations thereof.

Claim 17 (Currently amended): A system in accordance with claim

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1, claim 15 wherein said releasing means comprises a light-emitting diode.

Claim 18 (Currently amended): A system in accordance with claim

1, claim 15 wherein said releasing means comprises a light source that emits

photon energy at a wavelength of about 660 nanometers and transmits said

photon energy through said porous silicon and onto said interior surfaces of

said porous silicon to liberate said chemisorbed hydrogen atoms from said

dangling bond sites on said interior surfaces.

Claim 19 (Previously presented): A system in accordance with

claim 1 wherein said porous silicon is in a monocrystalline form.

Claim 20 (Currently amended): A system in accordance with claim

19 wherein said porous silicon is formed in a silicon wafer.

Claim 21 (Previously presented): A system in accordance with

claim 1 wherein said porous silicon is in a polycrystalline form.

Claim 22 (Currently amended): A system in accordance with claim

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1 wherein said porous silicon has been treated by a process selected from the

group consisting of crushing, milling, treatment with hydrofluoric acid and

methanol in the presence of electric current, treatment with potassium

hydroxide, treatment with hydrazine, wet etching, dry etching, deposition

electrodeposition of a noble metal such as palladium or platinum, conformal

vapor deposition of silicon, and non-conformal vapor deposition of silicon.

Claim 23 (Previously presented): A system in accordance with

claim 1 wherein said porous silicon is derived from molten silicon by

crystallization.

Claim 24 (Previously presented): A system in accordance with

claim 1 wherein said porous silicon is derived from silicon waste obtained from

a silicon process waste stream.

Claims 25-37 (Canceled)

Claim 38 (New): A system in accordance with claim 1, wherein said

releasing means is selected from the group consisting of light sources, current

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sources, voltage sources, and combinations thereof.

Claim 39 (New): A system in accordance with claim 1, wherein said

control unit further comprises means for controlling the silicon activation

energy of hydrogen on said porous silicon of said hydrogen storage member.

Claim 40 (New): A system in accordance with claim 15, wherein

said control unit further comprises means for controlling the silicon activation

energy of hydrogen on said porous mesh of crystalline silicon columns of said

hydrogen storage member.

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